

## **LISTING OF THE CLAIMS**

This listing of claims will replace all prior versions, and listings, of claims in the application:

### **Claim 1 (Currently Amended)**

A substrate treating apparatus for treating substrates, comprising:

a treating tank for receiving and treating the substrates;

cantilever-type holding means attached to an upper position of a main column through a mounting member to be movable, while holding the substrates ~~in a cantilever mode~~, between a treating position in said treating tank and a transfer position above said treating tank;

transport means for supporting the substrates and transferring the substrates to and from said holding means in said transfer position;

detecting means for detecting a posture variation of said holding means; and

correcting means for correcting a position of ~~one~~ of said holding means ~~and said transport means~~;

wherein said correcting means performs a correction according to the posture variation of said holding means detected by said detecting means in time of transfer of the substrates between said holding means and said transport means; ~~and~~

wherein said correcting means includes:

~~support means for supporting said holding means to be rockable about a cantilever point of said holding means, and drive means for rocking said holding means about said cantilever point;~~

a through hole formed in said mounting member constituting a cantilever proximal portion of said holding means;

a rigid member inserted into said through hole; and

positioning means attached to said mounting member for moving said holding means, by using said rigid member, in an opposite direction to a direction of movement of ~~a~~ said cantilever point of said holding means;

said positioning means including an actuator having a working piece movable into and out of an opening of said through hole to act on said rigid member.

**Claims 2-3 (Canceled)**

**Claim 4 (Original)**

A substrate treating apparatus as defined in claim 1, wherein said detecting means includes a laser displacement gauge or image processing means for performing a detection from a position spaced from said holding means.

**Claims 5-6 (Canceled)**

**Claim 7 (Original)**

A substrate treating apparatus as defined in claim 1, wherein said detecting means is mounted in a proximal portion of said holding means.

**Claims 8-9 (Canceled)**

**Claim 10 (Original)**

A substrate treating apparatus as defined in claim 4, wherein said detecting means is mounted in a proximal portion of said holding means.

**Claim 11 (Original)**

A substrate treating apparatus as defined in claim 7, wherein said detecting means is arranged to detect an angular acceleration or a distortion.

**Claim 12 (Original)**

A substrate treating apparatus as defined in claim 1, wherein said detecting means includes contact type detecting means for performing a detection while in contact with said holding means.

**Claim 13 (Canceled)****Claim 14 Original)**

A substrate treating apparatus as defined in claim 1, wherein said correcting means performs a correction based on a posture of said holding device unloaded with the substrates.

**Claim 15 (Canceled)****Claim 16 (Original)**

A substrate treating apparatus as defined in claim 1, wherein said correcting means performs a correction successively while said holding device shifts between an unloaded state and a substrate holding state.

**Claim 17 (Original)**

A substrate treating apparatus as defined in claim 1, wherein said correcting means includes advance/retreat drive means for advancing and retreating said support means along a substrate supporting side.

**Claims 18-20 (Canceled)**